OFFICIAL

PATENT Attorncy Docket No. 3381

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Michael P. Mittmann et al.

Serial No: 09/824,931

Filing Date: 4/3/2001

Title: Photolithographic Method and System for Efficient Mask Usage in Manufacturing DNA Arrays

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 Examiner: Ardin H. Marschel

Group Art Unit: 1631

AMENDMENT

Dear Examiner Marschel:

In response to the discussion at the Personal Interview conducted on July 20, 2004, Applicants respectfully submit the following amendments and remarks, and request reconsideration of the present application.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.